



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPL. NO. : 09/462,912 Confirmation No. 5646

APPLICANTS: Shigeo MORIYAMA, et al.

FILED : January 18, 2000

FOR : POLISHING APPARATUS AND METHOD FOR PRODUCING SEMICONDUCTORS USING THE APPARATUS

ART UNIT : 3723

EXAMINER : Dung Van Nguyen

DOCKET NO.: 29273/516

CUSTOMER NO.: 23838

COMMISSIONER FOR PATENTS
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AMENDMENT

SIR:

In response to the Final Office Action of July 7, 2004, the period for response having been extended herein to January 19, 2004 by payment of the requisite fee of \$980.00 for a Petition for Extension of Time Under 37 C.F.R. § 1.136(a), Applicants respectfully request that the Examiner reconsider his rejection in view of the remarks below. In addition, it is respectfully requested that the following clarifying amendment be entered to place this application in condition for allowance or better form for appeal.

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